

Written Examination EITP01 2019-03-21

Useful constants:

$$\hbar = 1.055 \times 10^{-34} \text{ J s}$$

$$k_B = 1.381 \times 10^{-23} \text{ J/K}$$

$$m_0 = 9.109 \times 10^{-31} \text{ kg}$$

$$\epsilon_0 = 8.85 \times 10^{-12} \text{ F m}^{-1}$$

$$e = q = 1.602 \times 10^{-19} \text{ C}$$

$$c = 2.998 \times 10^8 \text{ m/s}$$

1. Ballistic transport in QWFET

(15 p)

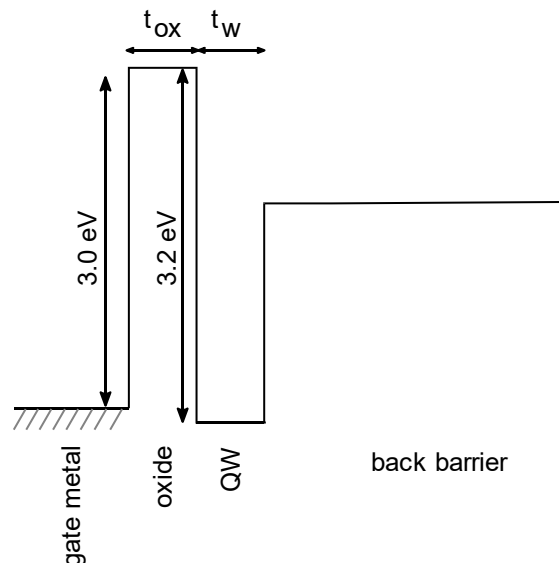
An InGaAs QWFET has the crosssectional band structure shown below, with the following parameters:

$$t_w = t_{ox} = 5 \text{ nm}$$

$$\epsilon_{ox} = 20, \epsilon_s = 14$$

$$m^* = 0.04m_0$$

A gate length of 70 nm and a width of 10 μm .

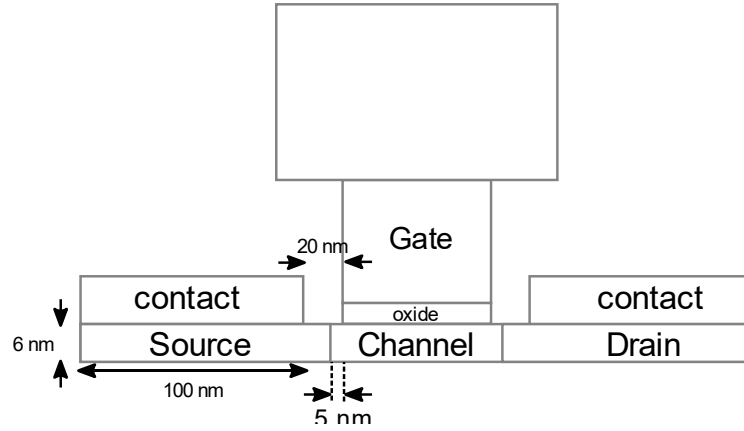


- Calculate the lowest two subband energy levels (E_1 and E_2) assuming an infinite well.
- Calculate the gate capacitance of the device when operated in the on-state.
- Explain the mechanism behind the current saturation in a ballistic transistor.
- The device is operated at $V_{DS} = V_{GS} = 0.5 \text{ V}$. Is the device in saturation?
- Calculate the (quasi-)ballistic current I_{DS} assuming a transmission coefficient of 0.6.
- Calculate the transconductance at these operation conditions.

2. High frequency operation

(15 p)

Another QWFET device as seen below has $C_{ox} = 0.033 \text{ F/m}^2$, $C_q = 0.028 \text{ F/m}^2$ and $C_C = 0.057 \text{ F/m}^2$, width of $10 \mu\text{m}$ and gate length of 90 nm . $g_m = 55 \text{ mS}$ and $g_d = 5 \text{ mS}$.

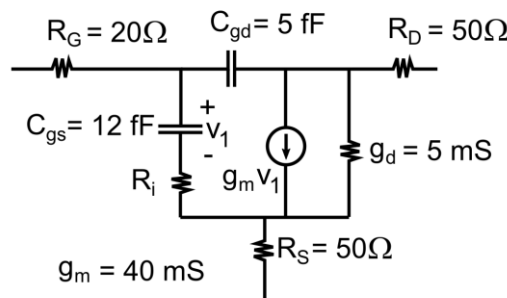


- Calculate the intrinsic value of f_T for this device.
- In reality, the contact and source and drain resistances lead to finite values of R_S and R_D . This device has a specific contact resistivity of $10 \Omega\mu\text{m}^2$, and a doping level of $1 \times 10^{19} \text{ cm}^{-3}$ and electron mobility of $500 \text{ cm}^2/\text{Vs}$ in the source/drain regions, while the channel itself has a mobility of $10000 \text{ cm}^2/\text{Vs}$ and doping level of $1.2 \times 10^{16} \text{ cm}^{-3}$. Due to a spacer process the low-doped channel region extends 5 nm outside of the gated area, while the gate-contact separation is 20 nm . Calculate R_S and R_D and comment on what is the largest contributor to the resistance.
- The fact that the contacts and gate are so closely spaced leads to a significant parasitic capacitance of $C_{gs,p} = C_{gd,p} = 5 \text{ fF}$. Calculate f_T including the effect of source/drain resistance and parasitic capacitances.

3. Power Gain

(15 p)

A transistor device is modelled by a hybrid- π small signal model (including parasitics):



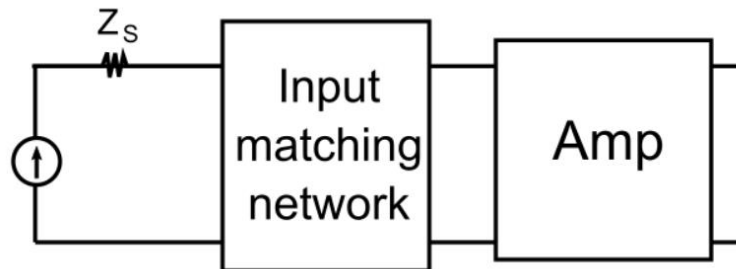
Here we have assumed that $C_{sd} = C_{dg} = C_{dd} = C_m = 0$ for simplicity.

- Explain the reason for introducing the channel resistance $R_i = 1/(1.4g_m)$.
- Determine the z-parameters of the model at $f = 100 \text{ GHz}$.
- Will the device be stable at this frequency?
- Use the proper metric to determine the power gain at this frequency.
- Determine f_{max} of the device. What could be done to improve f_{max} further?

4. Designing a Low noise amplifier

(15 p)

A transistor with $R = R_G + R_i = 44 \, \Omega$, $g_m = 20 \, \text{mS}$, $\gamma = 2/3$ and $C_{gs} = 10.5 \, \text{fF}$ is connected to a source with source impedance $Z_s = Z_0 = 50 \, \Omega$ and will be used as a low-noise amplifier at $f = 50 \, \text{GHz}$.



- Determine the source impedance that would optimize the noise figure and calculate the resulting minimum noise factor.
- Design an input matching network using $2.0 \, \mu\text{m}$ wide microstrip transmission line and stub to obtain an optimal low noise amplifier. Assume a dielectric spacer with dielectric constant of $\epsilon_r = 3$ and thickness of $5.0 \, \mu\text{m}$. (hint: Use a Smith chart)
- As an alternative, you now have the freedom to design the width of the transmission line freely. Design a matching network using a $\frac{\lambda}{4}$ transformer and a reactive element in series. (hint: Use a Smith chart)
- Which of these two networks is the most preferable? Motivate your answer.

Good luck!

Maximum score: 60 points